In the Claims:

Following is a complete listing of the claims pending in the application, as amended:

Please cancel claims 1-7 and add new claims 8-16.

- 8. (New) An apparatus for processing workpieces, comprising:
- a device support having a first alignment surface;
- a processing vessel carried by the device support at a carrying plane, the processing vessel being configured to receive at least one processing liquid;
- a workpiece support positioned to carry the workpiece at least proximate to the processing vessel;
- a drive unit operatively coupled to the workpiece support to move the workpiece support relative to the processing vessel; and
- a mounting portion coupled to the workpiece support and having a second alignment surface removably mated with the first alignment surface, with the workpiece support being supported relative to the device support only at or above the carrying plane.
- 9. (New) The apparatus of claim 18 wherein the mounting portion includes a base.
- 10. (New) The apparatus of claim 18 wherein the drive unit is operatively coupled to the workpiece support to rotate the workpiece support about a rotation axis.
- 11. (New) The tool of claim 18 wherein the processing vessel is configured to receive an electrochemical processing liquid.

- 12. (New) The apparatus of claim 18 wherein the processing vessel extends below the carrying plane.
- 13. (New) The apparatus of claim 18 wherein the workpiece support is configured to carry the workpiece in contact with a processing liquid.
- 14. (New) The apparatus of claim 18 wherein the workpiece support includes at least one contact assembly having at least one electrical contact positioned to make contact with the workpiece.
- 15. (New) The apparatus of claim 18 wherein the workpiece support includes at least one electrode and at least one sheath positioned to seal against a surface of the workpiece.
- 16. (New) The apparatus of claim 18 wherein the carrying plane includes an aperture in which the processing vessel is received.